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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/045,895	10/29/2001	Stephen Keetai Park	2000.029996/TT3586C	3826
23720 7	590 08/28/2003			
WILLIAMS, MORGAN & AMERSON, P.C. 10333 RICHMOND, SUITE 1100 HOUSTON, TX 77042			EXAMINER	
			LEE, HSIEN MING	
			ART UNIT	PAPER NUMBER
			2823	· · · · · · · · · · · · · · · · · · ·
			DATE MAILED: 08/28/2003	

Please find below and/or attached an Office communication concerning this application or proceeding.

			Applicant(s)			
		10/045,895	PARK, STEPHEN KEETAI			
Office Action Summary		Examiner	Art Unit			
		Hsien-Ming Lee	2823			
	The MAILING DATE of this communication a	appears on the cover sheet	with the correspondence address			
Period fo	• •					
THE N - Exter after - If the - If NO - Failu - Anyr earne	ORTENED STATUTORY PERIOD FOR REF MAILING DATE OF THIS COMMUNICATION asions of time may be available under the provisions of 37 CFR SIX (6) MONTHS from the mailing date of this communication. period for reply specified above is less than thirty (30) days, a reperiod for reply is specified above, the maximum statutory perion to reply within the set or extended period for reply will, by stately received by the Office later than three months after the mand patent term adjustment. See 37 CFR 1.704(b).	N. 1.136(a). In no event, however, may reply within the statutory minimum of od will apply and will expire SIX (6) N tute, cause the application to become	y a reply be timely filed thirty (30) days will be considered timely. MONTHS from the mailing date of this communication. BABANDONED (35 U.S.C. § 133).			
Status	Decrees to the communication (a) filed an O	16 June 2002				
1)⊠	Responsive to communication(s) filed on $\underline{0}$					
2a)□	,—	This action is non-final.				
3)	Since this application is in condition for allo closed in accordance with the practice und					
Dispositi	on of Claims	•				
4)⊠	Claim(s) 1-20,41 and 42 is/are pending in the	he application.				
	4a) Of the above claim(s) is/are withd	rawn from consideration.				
5)	Claim(s) is/are allowed.					
6)⊠	Claim(s) <u>1-20,41 and 42</u> is/are rejected.					
7)	Claim(s) is/are objected to.					
•	Claim(s) are subject to restriction and	d/or election requirement.				
	on Papers	·				
•	The specification is objected to by the Exami		ou the Eveniner			
10)[_]	The drawing(s) filed on is/are: a) ac	,				
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a). 11) The proposed drawing correction filed on is: a) approved b) disapproved by the Examiner.						
11/	If approved, corrected drawings are required in		g disapproved by the Examinor.			
12)[The oath or declaration is objected to by the	•				
•	under 35 U.S.C. §§ 119 and 120					
	Acknowledgment is made of a claim for fore	eign priority under 35 U.S.	C. § 119(a)-(d) or (f).			
•	☐ All b)☐ Some * c)☐ None of:					
	1. Certified copies of the priority docume	ents have been received.				
	2. Certified copies of the priority documents have been received in Application No					
* 6	3. Copies of the certified copies of the papplication from the International	Bureau (PCT Rule 17.2(a)).			
	See the attached detailed Office action for a l	•				
•	Acknowledgment is made of a claim for dome	, ,				
) \square The translation of the foreign language Acknowledgment is made of a claim for dome					
Attachmen						
2) Notic	e of References Cited (PTO-892) e of Draftsperson's Patent Drawing Review (PTO-948) mation Disclosure Statement(s) (PTO-1449) Paper No(s	5) 🔲 Notice	ew Summary (PTO-413) Paper No(s) of Informal Patent Application (PTO-152)			

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DETAILED ACTION

1. The objection to specification, claims 6, 11 and 16, 112-second-paragraph rejection to claims 1 and 7 and double patenting rejection, as set forth in the previous Office action, are withdrawn.

2. Claims 1-20, 41 and 42 are pending in the application.

Claim Objections

3. Claim 1 is objected to because of the following informalities: in-consistent term.

At line 15, "above the structure" should be – above the structure layer --.

Double Patenting

The nonstatutory double patenting rejection is based on a judicially created doctrine grounded in public policy (a policy reflected in the statute) so as to prevent the unjustified or improper timewise extension of the "right to exclude" granted by a patent and to prevent possible harassment by multiple assignees. See *In re Goodman*, 11 F.3d 1046, 29 USPQ2d 2010 (Fed. Cir. 1993); *In re Longi*, 759 F.2d 887, 225 USPQ 645 (Fed. Cir. 1985); *In re Van Ornum*, 686 F.2d 937, 214 USPQ 761 (CCPA 1982); *In re Vogel*, 422 F.2d 438, 164 USPQ 619 (CCPA 1970); and, *In re Thorington*, 418 F.2d 528, 163 USPQ 644 (CCPA 1969).

A timely filed terminal disclaimer in compliance with 37 CFR 1.321(c) may be used to overcome an actual or provisional rejection based on a nonstatutory double patenting ground provided the conflicting application or patent is shown to be commonly owned with this application. See 37 CFR 1.130(b).

Effective January 1, 1994, a registered attorney or agent of record may sign a terminal disclaimer. A terminal disclaimer signed by the assignee must fully comply with 37 CFR 3.73(b).

5. Claims 1-20, 41 and 42 rejected under the judicially created doctrine of obviousness-type double patenting as being unpatentable over claims 21-24 of U.S. Patent No. 6,303,486.

Although the conflicting claims are not identical, they are <u>not patentably distinct</u> from each other because of the reasons as follow.

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The following list is a comparison regarding limitations between the instant invention and the Patent:

the instant invention

- forming a first sacrificial dielectric layer
 above a structure layer and adjacent a contact;
- 2. forming a second sacrificial dielectric layer above the first sacrificial dielectric layer and the contact;
- 3. forming an opening in the second sacrificial dielectric layer, wherein at least a portion of the opening is above at least a portion of the contact;
- 4. forming a *copper layer* above the second sacrificial dielectric layer and *in the opening*;
- forming the copper interconnect by removing portions of the copper layer above the second sacrificial dielectric layer, leaving the copper interconnect in the opening;

the Patent

above a structure layer;
forming a sacrificial dielectric layer
above the first dielectric layer
and above the copper via;
forming a second opening in the
sacrificial dielectric layer above
at least a portion of the copper
via;

opening, the copper line contacting
the at least the portion of the copper
via;
planarizing a second dielectric
layer (claim 23); wherein the second
dielectric layer is formed above the

first dielectric layer and adjacent

to the copper line (claim 22);

forming a copper line in the second

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6. removing the first and second sacrificial dielectric layers;

- 7. forming a low dielectric constant

 dielectric layer above the structure

 and adjacent the copper interconnect

 and the contact; and
- 8. forming and patterning a mask layer above the low dielectric constant dielectric layer to have a mask layer opening above at least a portion of the copper interconnect (claim 4).

removing the sacrificial dielectric layer above the first dielectric layer (claim 21), i.e. inherently removing the sacrificial dielectric layer and the second dielectric layer;

forming a second dielectric layer, a

low dielectric constant material,
adjacent to the copper line (claims
22 and 23); and
forming and patterning a mask layer
above the second dielectric layer
to have a mask layer opening above
at least a portion of the second
copper structure (claim 24).

From the above comparison, it would have been obvious that a first dielectric layer of the Patent is equivalent to a first sacrificial dielectric layer of the instant invention; that a first sacrificial dielectric layer of the Patent is equivalent to a second sacrificial dielectric layer of the instant invention; that a copper via of the Patent is equivalent to a contact of the instant invention and that the low dielectric constant layer of the instant invention is equivalent to the second

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dielectric layer of the Patent. In addition, the features as shown in Figs. 15-16 of the Patent are equivalent to that of Figs. 5-6 of the instant invention.

Therefore, it would have been obvious to one of the ordinary skill in the art, at the time the invention was made, to recognize that both instant invention and the Patent claim a common subject matter, regardless the obvious variations, i.e. using different terms for describing same subject matters.

6. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Hsien-Ming Lee whose telephone number is 703-305-7341. The examiner can normally be reached on M-F (9:00 \sim 5:00).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Olik Chaudhuri can be reached on 703-306-2794. The fax phone number for the organization where this application or proceeding is assigned is (703) 305-3431.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is 703-308-0956.

Hsien-Ming Lee Examiner

Lee_

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August 19, 2003